FIG. i smooth etched surface છ surface migration 00000000 sputtering 000 00 o <u>a</u> bi-product homogenizing positive ion 9 00000000 00000000 00000000 radical Zn or Se

FIG. 2

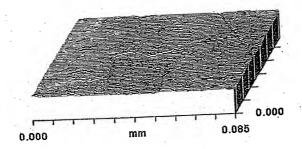


FIG. 3

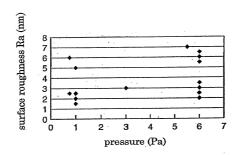


FIG. 4

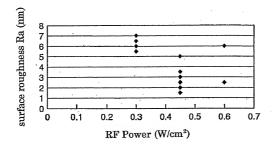


FIG. 5

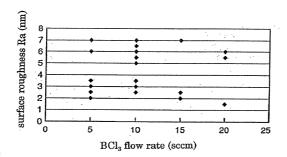


FIG. 6

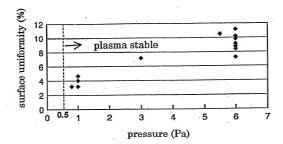


FIG. 7

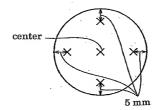


FIG. 8

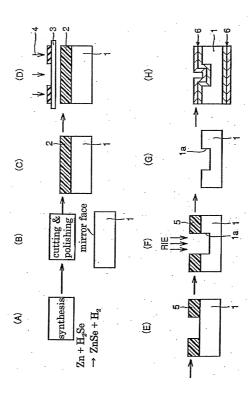


FIG. 9

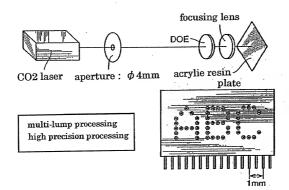


FIG. 10

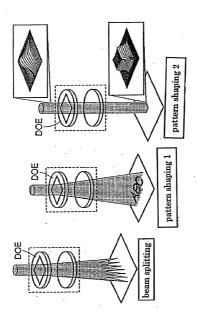
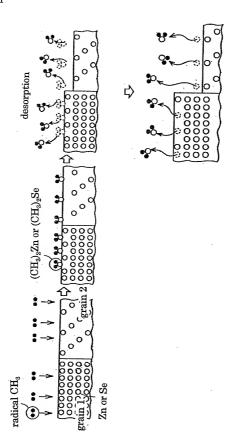


FIG. 11



FIĠ. 12

